



1762
hw/B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Willson et al.
App. No.: 09/905,718 GPAU: 1762
Filing Date: 05/16/2001 Examiner: Bernard Pianalto
Dkt. No.: PA27-02Q12 Conf. No.: 2731
For: METHOD AND SYSTEM FOR FABRICATING NANOSCALE PATTERNS IN
LIGHT CURABLE COMPOSITIONS USING AN ELECTRIC FIELD

INFORMATION DISCLOSURE STATEMENT TRANSMITTAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

- ☒ Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449
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to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

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- ☐ during the period specified in § 1.97(c). Each item of information contained in this Information Disclosure Statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement.

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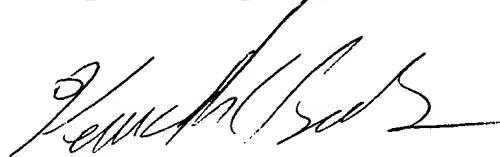
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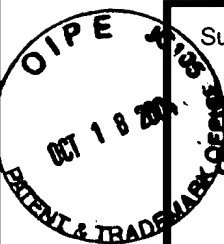
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(512) 339-7760
(512) 491-8918 (fax)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 1

Complete if Known

Application Number	09/905,718
Filing Date	05/16/2001
First Named Inventor	Willson et al.
Group Art Unit	1762
Examiner Name	Pianalto, Bernard D.
Attorney Docket Number	PA27-02Q12

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C1	Papirer et al., "The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography," August 1993, pp238-242, vol. 159, Issue 1.	
	C2	Abstract of Papirer et al., "The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography," August 1993, pp238-242, vol. 159, Issue 1.	
	C3	Hirai et al., "Mold Surface Treatment for Imprint Lithography," August 2001, pp 457-462, vol 14, No. 3.	
	C4	Abstract of Hirai et al., "Mold Surface Treatment for Imprint Lithography," August 2001, pp 457-462, vol 14, No. 3.	
	C5	Sung et al., "Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication," July 2003, pp. 808-818, vol. 255, no. 7.	
	C6	Abstract of Sung et al., "Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication," July 2003, pp. 808-818, vol. 255, no. 7.	
	C7	Roos et al., "Nanoimprint Lithography with a Commerical 4 Inch Bond System for Hot Embossing," October 2001, pp. 427-435, vol. 4343.	
	C8	Abstract of Roos et al., "Nanoimprint Lithography with a Commerical 4 Inch Bond System for Hot Embossing," October 2001, pp. 427-435, vol. 4343.	

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.

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